



EE C245 - ME C218 Introduction to MEMS Design Fall 2009

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Lecture Module 10: Resonance Frequency



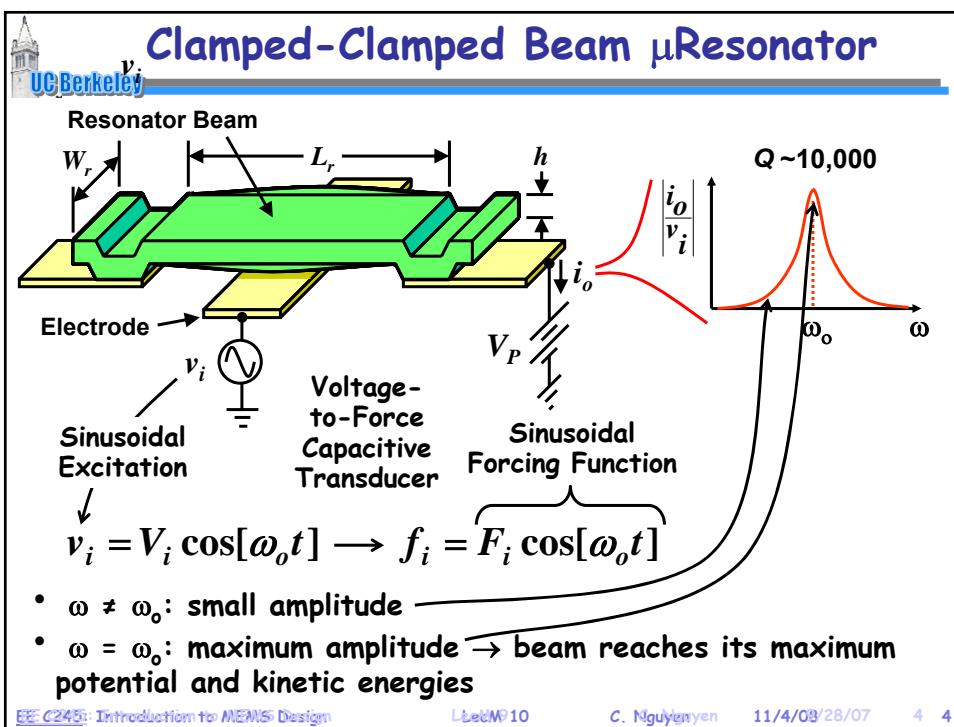
Lecture Outline

- Reading: Senturia, Chpt. 10: §10.5, Chpt. 19
- Lecture Topics:
 - ↳ Estimating Resonance Frequency
 - ↳ Lumped Mass-Spring Approximation
 - ↳ ADXL-50 Resonance Frequency
 - ↳ Distributed Mass & Stiffness
 - ↳ Folded-Beam Resonator

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Estimating Resonance Frequency

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Estimating Resonance Frequency

- Assume simple harmonic motion:

$$x(t) = x_o \cos(\omega t)$$

- Potential Energy:

$$W(t) = \frac{1}{2} k x^2(t) = \frac{1}{2} k x_o^2 \cos^2(\omega t)$$

- Kinetic Energy:

$$K(t) = \frac{1}{2} M \dot{x}^2(t) = \frac{1}{2} M x_o^2 \omega^2 \sin^2(\omega t)$$

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Estimating Resonance Frequency (cont)

- Energy must be conserved:
 - ↪ Potential Energy + Kinetic Energy = Total Energy
 - ↪ Must be true at every point on the mechanical structure

Occurs at peak displacement $\nwarrow W_{\max} = \frac{1}{2} k x_o^2$ Maximum Potential Energy Stiffness Displacement Amplitude	Occurs when the beam moves through zero displacement $\downarrow K_{\max} = \frac{1}{2} M \omega^2 x_o^2$ Maximum Kinetic Energy Mass Radian Frequency
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- Solving, we obtain for resonance frequency:

$$\omega = \sqrt{\frac{k}{M}}$$

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Example: ADXL-50

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- The proof mass of the ADXL-50 is many times larger than the effective mass of its suspension beams
 - Can ignore the mass of the suspension beams (which greatly simplifies the analysis)
- Suspension Beam: $L = 260 \mu\text{m}$, $h = 2.3 \mu\text{m}$, $W = 2 \mu\text{m}$

Fixed Capacitor Plates

Proof Mass

Sense Finger

Suspension Beam in Tension

Applied Acceleration

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Lumped Spring-Mass Approximation

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- Mass is dominated by the proof mass
 - 60% of mass from sense fingers
 - Mass = $M = 162 \text{ ng}$ (nano-grams)
- Suspension: four tensioned beams
 - Include both bending and stretching terms [A.P. Pisano, BSAC Inertial Sensor Short Courses, 1995-1998]

Bending compliance k_b^{-1}

Stretching compliance k_{st}^{-1}

$F/4$

$F/4$

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ADXL-50 Suspension Model

• Bending contribution:

$$k_b^{-1} = (1/k_c + 1/k_e) = 2 \left[\frac{(L/2)^3}{3E(Wh^3/12)} \right] = \frac{L^3}{EWh^3} = 4.2 \mu\text{m}/\mu\text{N}$$

• Stretching contribution:

$$k_{st}^{-1} = L/S = \frac{L}{\sigma_r Wh} = 1.14 \mu\text{m}/\mu\text{N}$$

$$F_y = S \sin \theta \approx S(x/L) = \underbrace{\left(\frac{S}{L}\right)x}_{\text{"}}$$

• Total spring constant: add bending to stretching
(since they are in parallel)

$$k = 4(k_b + k_{st}) = 4(0.24 + 0.88) = 4.5 \mu\text{N}/\mu\text{m}$$

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ADXL-50 Resonance Frequency

• Using a lumped mass-spring approximation:

$$f = \frac{1}{2\pi} \sqrt{\frac{k}{M}} = \frac{1}{2\pi} \sqrt{\frac{4.48 \text{ N/m}}{162 \times 10^{-12} \text{ kg}}} = 26.5 \text{ kHz}$$

• On the ADXL-50 Data Sheet: $f_o = 24 \text{ kHz}$

- ↳ Why the 10% difference?
- ↳ Well, it's approximate ... plus ...
- ↳ Above analysis does not include the frequency-pulling effect of the DC bias voltage across the plate sense fingers and stationary sense fingers ... something we'll cover later on ...

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Distributed Mechanical Structures

- Vibrating structure displacement function:

$$y(x,t) = \hat{y}(x) \cos(\omega t)$$

Maximum displacement function
(i.e., mode shape function)
Seen when velocity $\dot{y}(x,t) = 0$

- Procedure for determining resonance frequency:
 - Use the static displacement of the structure as a trial function and find the strain energy W_{\max} at the point of maximum displacement (e.g., when $t=0, \pi/\omega, \dots$)
 - Determine the maximum kinetic energy when the beam is at zero displacement (e.g., when it experiences its maximum velocity)
 - Equate energies and solve for frequency

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Maximum Kinetic Energy

- Displacement: $y(x,t) = \hat{y}(x) \cos[\omega t]$
- Velocity: $v(x,t) = \frac{\partial y(x,t)}{\partial t} = -\omega \hat{y}(x) \sin[\omega t]$
- At times $t = \pi/(2\omega), 3\pi/(2\omega), \dots$

$$y(x,t) = 0$$

Velocity topographical mapping

- The displacement of the structure is $y(x,t) = 0$
- The velocity is maximum and all of the energy in the structure is kinetic (since $W=0$):

$$v(x, (2n+1)\pi/(2\omega)) = -\omega \hat{y}(x)$$

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Maximum Kinetic Energy (cont)

At times $t = \pi/(2\omega), 3\pi/(2\omega), \dots$

Velocity: $v(x, (2n+1)\pi/(2\omega)) = -\omega\hat{y}(x)$

$$dK = \frac{1}{2} \cdot dm \cdot [v(x, t)]^2$$

$$dm = \rho(Wh \cdot dx)$$

Maximum kinetic energy:

$$K_{\max} = \int_0^L \frac{1}{2} \rho Wh dx v^2(x, t') = \int_0^L \frac{1}{2} \rho Wh \omega^2 \hat{y}^2(x) dx$$

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The Raleigh-Ritz Method

Equate the maximum potential and maximum kinetic energies:

$$K_{\max} = \int_0^L \frac{1}{2} \rho Wh \omega^2 \hat{y}^2(x) dx = W_{\max}$$

Rearranging yields for resonance frequency:

$$\omega = \sqrt{\frac{W_{\max}}{\int_0^L \frac{1}{2} \rho Wh \hat{y}^2(x) dx}}$$

ω = resonance frequency
 W_{\max} = maximum potential energy
 ρ = density of the structural material
 W = beam width
 h = beam thickness
 $\hat{y}(x)$ = resonance mode shape

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Example: Folded-Beam Resonator

Folded-beam suspension

Shuttle w/ mass M_s

Folding truss w/ mass $M_t/2$

Anchor

$h = \text{thickness}$

- Derive an expression for the resonance frequency of the folded-beam structure at left.

Use Rayleigh-Ritz method.

$$KE_{\max} = PE_{\max}$$

Kinetic Energy:

$$KE_{\max} = \underbrace{KE_S}_{\text{shuttle truss beams}} + \underbrace{KE_t}_{\text{mass of both trusses}} + \underbrace{\frac{1}{2} \int N_b^2 dM_b}_{\text{Must integrate since the beam velocity is a function of location } y!}$$

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Get Kinetic Energies

Folded-beam suspension

Shuttle w/ mass M_s

Folding truss w/ mass $M_t/2$

Anchor

$h = \text{thickness}$

Velocity of the shuttle: $N_s = \omega_0 \ddot{x}_0$

Resonance Freq. Maximum Displacement Amplitude

$$\therefore KE_s = \frac{1}{2} N_s^2 M_s = \frac{1}{2} \omega_0^2 \ddot{x}_0^2 M_s$$

Velocity of the truss: $N_t = \frac{1}{2} N_s = \frac{1}{2} \omega_0 \ddot{x}_0$

$$\therefore KE_t = \frac{1}{2} \left(\frac{1}{2} \omega_0 \ddot{x}_0 \right)^2 M_t = \frac{1}{8} \omega_0^2 \ddot{x}_0^2 M_t$$

Velocity of the beam segments:
 ⇒ assume the mode shape is the same as the static displacement shape
 ⇒ For segment AB:

$$\ddot{x}(y) = \frac{F_x}{48 E I_z} (3Ly^2 - 2y^3) \quad 0 \leq y \leq L \quad (1)$$

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Folded-Beam Suspension

$\ddot{x}(y) = \frac{F_x}{48EI_z} (3Ly^2 - 2y^3) \quad 0 \leq y \leq L$

Case: $y=0$ $\ddot{x}(y=0) = 0 \checkmark$

Case: $y=L$ $\ddot{x}(y=L) = \frac{F_x}{48EI_z} L^3 \rightarrow k = \frac{(F_x M)}{X_0} = \frac{12 EI_z}{L^3} = \frac{k_c}{2} \checkmark$

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Get Kinetic Energies (cont)

At $y=L$: $x(L) = \frac{X_0}{2} = \frac{F_x L^3}{48EI_z}$

Substituting into (1):

$$\ddot{x}(y) = \frac{X_0}{2} \left[3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]$$

which yields for velocity:

$$v_b(y) |_{[AB]} = \frac{X_0}{2} \left[3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right] \omega_0$$

Plugging into the expression for KE_b :

$$KE_{[AB]} = \frac{1}{2} \int_0^{X_0/2} \frac{X_0^2 \omega_0^2}{4} \left[3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]^2 dM_{[AB]}$$

Static mass of beam [AB] = $\frac{X_0^2 \omega_0^2 M_{[AB]}}{8L} \int_0^{X_0/2} \left[3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]^2 dy$

$KE_{[AB]} = \frac{13}{280} X_0^2 \omega_0^2 M_{[AB]}$

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Get Kinetic Energies (cont)

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Folded-beam suspension

Shuttle w/ mass M_s

Folding truss w/ mass $M_t/2$

Anchor

$h = \text{thickness}$

For segment CD:

$$v_b(y)|_{(CD)} = X_0 \left[1 - \frac{3}{2} \left(\frac{y}{L} \right)^2 + \left(\frac{y}{L} \right)^3 \right] \omega_0$$

Thus:

$$KE_{(CD)} = \frac{X_0^2 \omega_0^2 M_{(CD)}}{2L} \int_0^L \left[1 - \frac{3}{2} \left(\frac{y}{L} \right)^2 + \left(\frac{y}{L} \right)^3 \right] dy$$

$$KE_{(CD)} = \frac{83}{280} X_0^2 \omega_0^2 M_{(CD)}$$

Static mass of beam [CD]

Let $M_b \triangleq \text{total mass of the 8 beams.}$

Then: $M_{(AB)} = M_{(CD)} = \frac{1}{8} M_b$

Thus:

$$KE_b = 4 KE_{(AB)} + 4 KE_{(CD)} = \frac{6}{35} X_0^2 \omega_0^2 M_b$$

and

$$KE_{\max} = X_0^2 \omega_0^2 \left[\frac{1}{2} M_s + \frac{1}{8} M_t + \frac{6}{35} M_b \right]$$

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Get Potential Energy & Frequency

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Folded-beam suspension

Shuttle w/ mass M_s

Folding truss w/ mass $M_t/2$

Anchor

$h = \text{thickness}$

PE_{max} is simply the work done to achieve maximum deflection: $\approx k_c$

$$PE_{\max} = \frac{1}{2} k_x X_0^2$$

Thus, using Raleigh-Ritz:

$$KE_{\max} = PE_{\max}$$

$$X_0^2 \omega_0^2 \left[\frac{1}{2} M_s + \frac{1}{8} M_t + \frac{6}{35} M_b \right] = \frac{1}{2} k_x X_0^2$$

$$\omega_0 = \left[\frac{k_x}{M_{eq}} \right]^{\frac{1}{2}} = k_c$$

where $M_{eq} = M_s + \frac{1}{8} M_t + \frac{12}{35} M_b$

(Resonance Frequency of a Folded-Beam Suspended Shuttle)

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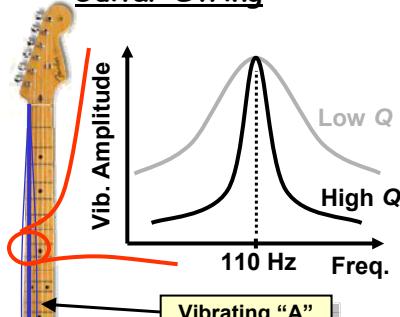
Brute Force Methods for Resonance Frequency Determination

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Basic Concept: Scaling Guitar Strings

Guitar String



Vib. Amplitude

Low Q

High Q

110 Hz

Freq.

Vibrating "A" String (110 Hz)

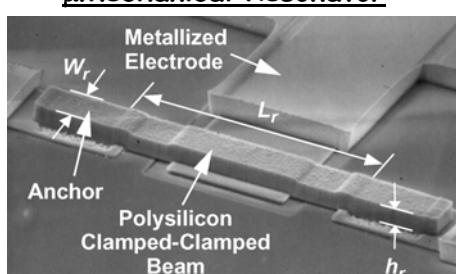
Stiffness

Freq. Equation:

$$f_o = \frac{1}{2\pi} \sqrt{\frac{k_r}{m_r}}$$

Mass

μMechanical Resonator



Metallized Electrode

Anchor

Polysilicon Clamped-Clamped Beam

[Bannon 1996]

Transmission [dB]

Frequency [MHz]

Performance:

- $L_r = 40.8 \mu\text{m}$
- $m_r \sim 10^{-13} \text{ kg}$
- $W_r = 8 \mu\text{m}$, $h_r = 2 \mu\text{m}$
- $d = 1000 \text{ \AA}$, $V_p = 5 \text{ V}$
- Press. = 70 mTorr

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Anchor Losses

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Fixed-Fixed Beam Resonator

Anchor, Gap, Electrode

$Q = 300 \text{ at } 70\text{MHz}$

Problem: direct anchoring to the substrate \Rightarrow anchor radiation into the substrate \Rightarrow lower Q

Solution: support at motionless nodal points \Rightarrow isolate resonator from anchors \Rightarrow less energy loss \Rightarrow higher Q

Free-Free Beam Resonator

Supporting Beams, Anchor, Free-Free Beam, $\lambda/4$, L_r

$Q = 15,000 \text{ at } 92\text{MHz}$

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92 MHz Free-Free Beam μResonator

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- Free-free beam μmechanical resonator with non-intrusive supports \Rightarrow reduce anchor dissipation \Rightarrow higher Q

Drive Electrode, Support Beams, Flexural-Mode Beam, Anchor, Ground Plane and Sense Electrode, $13.1\mu\text{m}$, $1\mu\text{m}$, $10.4\mu\text{m}$

Design/Performance:

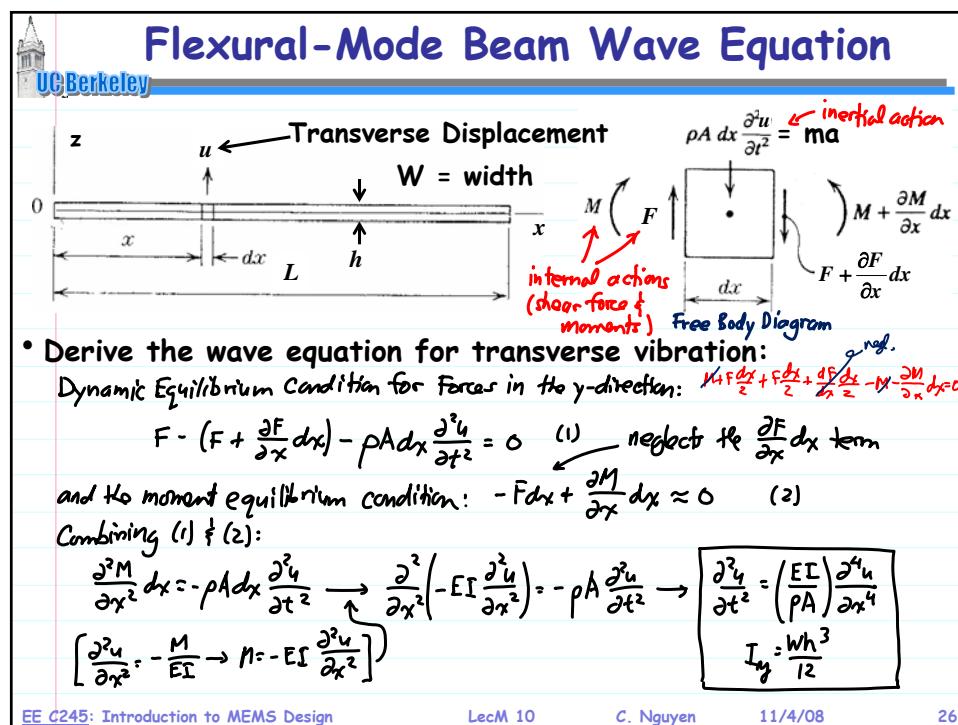
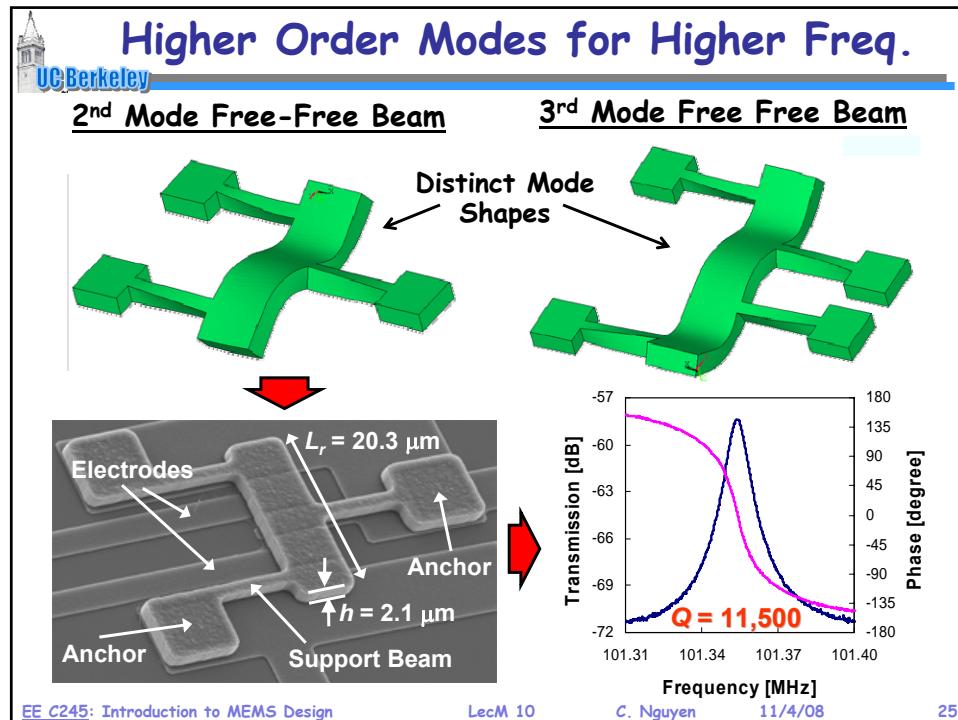
- $L_f=13.1\mu\text{m}$, $W_f=6\mu\text{m}$
- $h=2\mu\text{m}$, $d=1000\text{\AA}$
- $V_p=28-76\text{V}$, $W_s=2.8\mu\text{m}$
- $f_o=92.25\text{MHz}$
- $Q=7,450$ @ 10mTorr

[Wang, Yu, Nguyen 1998]

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Transmission [dB] vs Frequency [MHz]

92.25 MHz $Q = 7,450$



Example: Free-Free Beam

• Determine the resonance frequency of the beam
 • Specify the lumped parameter mechanical equivalent circuit
 • Transform to a lumped parameter electrical equivalent circuit
 • Start with the flexural-mode beam equation:

$$\frac{\partial^2 u}{\partial t^2} = \left(\frac{EI}{\rho A} \right) \frac{\partial^4 u}{\partial x^4}$$

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Free-Free Beam Frequency

• Substitute $u = u_1 e^{j\omega t}$ into the wave equation:

$$\frac{\partial^4 u}{\partial x^4} = \left(\omega^2 \frac{\rho A}{EI} \right) u \quad (1)$$

• This is a 4th order differential equation with solution:

$$u(x) = \underline{A} \cosh kx + \underline{B} \sinh kx + \underline{C} \cos kx + \underline{D} \sin kx \quad (2)$$

Given the mode shape during resonance vibration.

• Boundary Conditions:

At $x = 0$	$\dot{u}(x) = 0$	$u(x) = 0$
$\frac{\partial^2 u}{\partial x^2} = 0$	$\frac{\partial^2 u}{\partial x^2} = 0$	$M = 0$ (Bending moment)
$\frac{\partial^3 u}{\partial x^3} = 0$	$\frac{\partial^3 u}{\partial x^3} = 0$	$\frac{\partial M}{\partial x} = 0$ (Shearing force)

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Free-Free Beam Frequency (cont)

• Applying B.C.'s, get $A=C$ and $B=D$, and

$$\begin{bmatrix} (\cosh k\ell - \cos k\ell) & (\sinh k\ell - \sin k\ell) \\ (\sinh k\ell + \sin k\ell) & (\cosh k\ell - \cos k\ell) \end{bmatrix} \begin{bmatrix} \alpha \\ \beta \end{bmatrix} = 0 \quad (3)$$

• Setting the determinant = 0 yields

$$\cos k\ell = \frac{1}{\cosh k\ell}$$

• Which has roots at

$$k_1\ell = 4.730 \quad k_2\ell = 7.853 \quad k_3\ell = 10.996$$

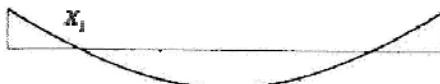
• Substituting (2) into (1) finally yields: These values of $k_n\ell$ correspond to the different modes of vibration!

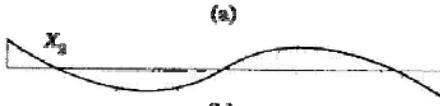
$$k^4 = \frac{\rho A}{EI} \omega^2 \rightarrow f_n = \frac{(k_n\ell)^2}{2\pi\ell^2} \sqrt{\frac{EI}{\rho A}} \quad \left[\begin{array}{l} \text{Free-Free Beam} \\ \text{Frequency Equation} \end{array} \right]$$

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Higher Order Free-Free Beam Modes

Mode	n	Nodal Points	$k_n\ell$	f_n/f_1
Fundamental (f_1)	1	2	4.730	1.000
1st Harmonic	2	3	7.853	2.757
2nd Harmonic	3	4	10.996	5.404
3rd Harmonic	4	5	14.137	8.932
4th Harmonic	5	6	17.279	13.344 ← More than 10x increase

(a)  Fundamental Mode ($n=1$)

(b)  1st Harmonic ($n=2$)

(c)  2nd Harmonic ($n=3$)

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Mode Shape Expression

- The mode shape expression can be obtained by using the fact that $A=C$ and $B=D$ into (2), yielding

$$u_x = \frac{A}{B} \left[\left(\frac{\omega}{\omega_0} \right) (\cosh kx + \cos kx) + (\sinh kx + \sin kx) \right]$$

- Get the amplitude ratio by expanding (3) [the matrix] and solving, which yields

$$\frac{A}{B} = \frac{\sin k\ell - \sinh k\ell}{\cosh k\ell - \cos k\ell}$$

- Then just substitute the roots for each mode to get the expression for mode shape



Fundamental Mode ($n=1$)

[Substitute $k_1\ell = 4.730$]